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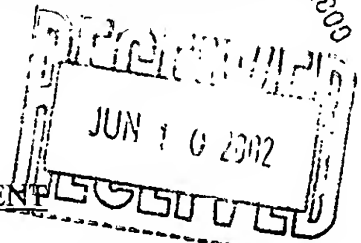
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Peter de Groot et al.  
Serial No. : 10/053,106  
Filed : November 2, 2001  
Title : HEIGHT SCANNING INTERFEROMETRY METHOD AND APPARATUS  
INCLUDING PHASE GAP ANALYSIS



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INFORMATION DISCLOSURE STATEMENT

Applicant submits the references listed on the attached form PTO-1449, copies of which are enclosed.

This statement is being filed within three months of the filing date of the application or before the receipt of a first Office action on the merits. Please apply any charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: 5/28/02

*[Signature]*

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\*See attached document certifying that Marc M. Wefers has limited recognition to practice before the U.S. Patent and Trademark Office under 37 C.F.R. § 10.9(b).

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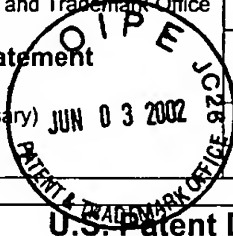
I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, Washington, D.C. 20231.

28 May 2002  
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*[Signature]*  
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Diane C. Brown  
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Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 09712-132001	Application No. 10/053,106
<b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Peter de Groot et al.	
		Filing Date November 2, 2001	Group Art Unit



### U.S. Patent Documents

Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	6,195,168 B1	02/2001	De Lega et. al.	356	497	
	AB	5,398,113	03/1995	De Groot	356	360	
	AC	5,784,164	07/1998	Deck et. al.	356	511	
	AD	5,402,234	03/1995	Deck	356	497	
	AE	5,471,303	11/1995	Ai et. al.	356	497	

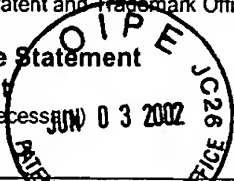
### Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AF							
	AG							
	AH							
	AI							
	AJ							

### Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
	AK	P. de Groot and Leslie Deck, "Surface profiling by analysis of white-light interferograms in the spatial frequency domain," J. Mod. Opt. 42(2), 389-401 (1995).
	AL	T. Dresel, G. Hausler and H. Venzke, "Three-dimensional sensing of rough surfaces by coherence radar," Appl. Opt. 31(7), 919-925 (1992).
	AM	Gordon S. Kino and Stanley S. C. Chim, "Mirau correlation microscope," Appl. Opt. 29(26), 3775-3783 (1990).
	AN	Kieran G. Larkin, "Efficient nonlinear algorithm for envelope detection in white light interferometry," J. Opt. Soc. Am. A 4, 832- 843 (1996)
	AO	M.-C. Park and S.-W. Kim, "Direct quadratic polynomial fitting for fringe peak detection of white light scanning interferograms", Opt. Eng. 39(4) 952-959 (2000)
	AP	A. Harasaki, J. Schmit and J. C. Wyant, "Improved vertical-scanning interferometry", Appl. Opt. 39(39), 2107-2115 (2000)
	AQ	B.L. Danielson and C.Y. Boisrobert, "Absolute optical ranging using low coherence interferometry," Appl. Opt. 30(21), 2975-2979 (1991)
	AR	A. Harasaki and J. C. Wyant, "Fringe modulation skewing effect in white-light vertical scanning interferometry," Appl. Opt. 39(13), 2101-2106 (2000).

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

Substitute Form PTO-1449 (Modified)  <b>Information Disclosure Statement</b> <b>by Applicant</b> (Use several sheets if necessary)  (37 CFR §1.98(b))	U.S. Department of Commerce Patent and Trademark Office  	Attorney's Docket No. 09712-132001	Application No. 10/053,106
		Applicant Peter de Groot et al.	
		Filing Date November 2, 2001	Group Art Unit

	AS	D. C. Ghiglia and J. J. Pritt, "Two-dimensional phase unwrapping: Theory, algorithms and software" (John Wiley & Sons, Inc., New York, 1998), p. 93.
	AT	J. Schwider and L. Zhou, "Dispersive interferometric profilometer," Opt. Lett. 19(13), 995-997 (1994).
	AU	S.W. Kim and G.H. Kim, "Thickness-profile measurement of transparent thin-film layers by white-light scanning interferometry," Appl. Opt. 38(28) (1999).
	AV	M. Davidson, K. Kaufman, and I. Mazar, "The coherence probe microscope," Solid State Technology, 30(9) 57-59 (1987).
	AW	J.C. Wyant, "How to extend interferometry for rough-surface tests," Laser Focus World, 131-135 (September 1993).
	AX	P. de Groot and L. Deck, "Three-dimensional imaging by sub-Nyquist sampling of white-light interferograms," Opt. Lett. 18(17), 1462-1464 (1993).
	AY	P. Sandoz, R. Devillers, and A. Plata, "Unambiguous profilometry by fringe-order identification in white-light phase shifting interferometry," J. Mod. Opt. 44, 519-534 (1997).
	AZ	P.J. Caber, S.J. Martinek, and R.J. Niemann, "A new interferometric profiler for smooth and rough surfaces," SPIE 2088, 195-203 (1993).
	AAA	A. Pfortner and J. Schwider, "Dispersion error in white-light Linnik interferometers and its implications for evaluation procedures," Appl. Opt. 40(34) 6223-6228 (2001).
	ABB	P. de Groot, X. Colonna de Lega, J. Kramer, and M. Turzhitsky, "High precision surface inspection on the microscale by broadband interferometry", Proc. Fringe 2001, The 4 <sup>th</sup> International Workshop on Automatic Processing of Fringe Patterns, Wolfgang Osten and Werner Juptner Eds., Elsevier, pp. 333-340 (2001).
	ACC	L. Deck and P. de Groot, "High-speed non-contact profiler based on scanning white light interferometry," Appl. Opt. 33(31), 7334-7338 (November 1, 1994).

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EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	



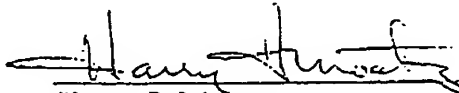
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Expires: January 7, 2003

  
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Director of Enrollment and Discipline